

CLAIM LISTING:

This listing of claims will replace all prior versions and listings of claims in the application:

1. (Currently amended) A device comprising:
a housing;
one or more ion generators for generating ions of positive polarity and ions of negative polarity;
~~one or more~~ a plurality of ion emitters for emitting ions of positive polarity and ions of negative polarity; wherein said ~~one or more~~ plurality of ion emitters ~~[[is/]]~~are situated adjacent, but outside said housing.
2. (Original) The device of claim 1, wherein said ions form an ion concentration outside said housing and at a distance from a user's hair.
3. (Original) The device of claim 2, wherein said hair is encompassed by said ion concentration.
4. (Original) The device of claim 1, further comprising at least one blower for generating airflow to be applied to hair.
5. (Original) The device of claim 4, wherein said housing has at least one aperture disposed therein forming an air outlet for directing said airflow.
6. (Currently amended) The device of claim 5, wherein said ~~one or more~~ plurality of ion emitters ~~[[is/]]~~are situated at a distance from said airflow.
7. (Original) The device of claim 6, further comprising at least one attachment for cooperating with said air outlet to manipulate said airflow.

8. (Original) The device of claim 7, wherein said at least one attachment is configured to variably control aeration of said positive and negative ions into said airflow.

9. (Original) The device of claim 8, wherein said at least one blower alters said airflow velocity, thereby controlling aspiration of said positive and negative ions into said airflow.

10. (Currently amended) The device of claim 1, wherein said ~~one or more~~ plurality of ion generators ~~[[is/]]~~ are configured to provide a variety of voltage outputs, as well as to generate combinations of positive and negative ions.

11. (Currently amended) The device of claim 1, wherein said ~~one or more~~ plurality of ion emitters ~~[[is/]]~~ are positioned in a casing formed on said housing.

12. (Original) The device of claim 11, wherein said casing is selectively removable from said housing.

13. (Currently amended) The device of claim 1, wherein said ~~one or more~~ plurality of ion emitters ~~[[is/]]~~ are formed from a conductive metal.

14. (Currently amended) The device of claim 1, wherein said ~~one or more~~ plurality of ion emitters ~~[[is/]]~~ are formed from a conductive polymer.

15. (Currently amended) The device of claim 1, wherein said ~~one or more~~ plurality of ion emitters ~~[[is/]]~~ are formed from a conductive silicon.

16. (Currently amended) The device of claim 1, wherein said plurality of ion emitters form an array.

17. (Currently amended) The device of claim 1, wherein said ~~one or more~~
plurality of ion emitters create an ion concentration having a negative polarity.

18. (Currently amended) The device of claim 1, wherein said ~~one or more~~
plurality of ion emitters create an ion concentration having a positive polarity.

19. (Currently amended) The device of claim 1, wherein said ~~one or more~~
plurality of ion emitters create an ion concentration having both a positive and negative
polarity.

20. (Currently amended) The device of claim 1, wherein said plurality of ion
emitters ~~[[is/]]~~ are arranged to generate a predictable area of concentrated ions and to
minimize any dilution resulting from direct exposure to said airflow.

21. (Currently amended) A method for treating hair comprising the steps of:
providing a device having a housing with at least one air outlet disposed therein,
a blower for generating an airflow stream, one or more ion generators, and one or more
ion emitters disposed outside, but adjacent to said housing and spaced a distance from
said airflow exiting said air outlet;

applying said blower generated airflow toward hair for drying and/or styling;
[[and]]

generating an ion concentration having a certain area and spaced a certain
distance from said airflow to minimize any dilution resulting from direct exposure to said
airflow; and

providing at least one attachment for cooperating with said air outlet of said
housing for controlling the mixing of said ion concentration with said airflow stream and
hair.

22. (Canceled).

23. (Currently amended) The method for treating hair of claim ~~[[22]]~~ 21, wherein said at least one attachment is configured to variably control aspiration of said positive and negative ions into said airflow.

24. (Original) The method for treating hair of claim 23, wherein said at least one blower alters said airflow velocity, thereby controlling said aspiration of said positive and negative ions into said airflow.

25. (Original) The method for treating hair of claim 21, wherein said at least one ion generator is configured to provide a variety of voltage outputs, as well as to generate combinations of positive and negative ions.

26. (Original) The method for treating hair of claim 21, wherein said one or more ion emitters is/are positioned in a casing formed on said housing.

27. (Original) The method for treating hair of claim 21, wherein said one or more ion emitters is/are formed from a conductive metal.

28. (Original) The method for treating hair of claim 21, wherein said one or more ion emitters is/are formed from a conductive polymer.

29. (Original) The method for treating hair of claim 21, wherein said one or more ion emitters is/are formed from a conductive silicon.

30. (Currently amended) The method for treating hair of claim 21, wherein said one or more ion emitters form an array.

31. (Original) The method for treating hair of claim 21, wherein said one or more ion emitters create an ion concentration having a negative polarity.

32. (Original) The method for treating hair of claim 21, wherein said one or more ion emitters create an ion concentration having a positive polarity.

33. (Original) The method for treating hair of claim 21, wherein said one or more ion emitters create an ion concentration having both a positive and negative polarity.

34. (Original) The method for treating hair of claim 21, wherein said one or more ion emitters is/are arranged to generate a predictable area of concentrated ions and to minimize any dilution resulting from direct exposure to said airflow.